

a second object table to hold a substrate;

a vacuum chamber provided with a first vacuum generator constructed and arranged to provide a vacuum beam path for the projection beam;

a projection system to project the patterned beam onto a target portion of the substrate;

at least one conduit communicating a utility to a component of said lithographic projection apparatus moveable in at least one degree of freedom in said vacuum chamber;

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G20 a conduit shield substantially enclosing a space comprising the at least one conduit and substantially separating said vacuum chamber from the space comprising the at least one conduit, said conduit shield being constructed and arranged to allow for movement of the component in said at least one degree of freedom, and

a second vacuum generator constructed and arranged to provide a vacuum in the space comprising the at least one conduit.

See the attached Appendix for the changes made to effect the above claim.